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MEMS Inertial Sensors, 2nd Edition

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Message from the Guest Editors

Dear Colleagues,

MEMS technology is revolutionary to inertial measurement because of its unique advantages, i.e., miniaturized size, low power consumption, high dynamic range, and low cost. It is particularly suitable for navigation and control systems in robotics, autonomous cars, personal indoor scenarios, and other military applications. Nevertheless, MEMS inertial sensors still suffers scientific barriers towards high-end applications. Major challenges include but are not limited to microfabrication processes, new materials, device design and optimization, simulation techniques, interface circuits, measurement instrumentation, signal processing, and sensor fusion. This Special Issue calls for original research papers and reviews with state-of-the-art results in the relevant topics.

Dr. Chong Li
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Guest Editors













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Message from the Editor-in-Chief

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